



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Hashim, et al.

Serial No.: 09/138,429

Filed: August 24, 1998

For: Collimated and Long Throw  
Magnetron Sputtering of  
Nickel/Iron Films for Magnetic  
Recording Head Applications

Group Art Unit: 1753

Examiner: Mercado, J.

Confirmation No.: 4066

BOX AF  
Assistant Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

CERTIFICATE OF MAILING 37 C.F.R. 1.8	
I hereby certify that this correspondence is being deposited on June 11, 2001, with the U. S. Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231.	
Date 6/11/01	Signature B. Todd Patterson

## RESPONSE TO FINAL OFFICE ACTION DATED APRIL 9, 2001

In response to the Final Office Action dated April 9, 2001, having a shortened statutory period for response set to expire on June 9, 2001, Applicants request reconsideration of the claims pending in the application for reasons discussed below. The Commissioner is authorized to charge Deposit Account No. 20-0782/AMAT/2406.X1/NAN for any fees required in conjunction with this response.

**PENDING CLAIMS:**

1. An apparatus for depositing a magnetic film, comprising:  
a sputtering chamber containing a target, a substrate support having a surface that is separated from the target, and a grounded collimator positioned between the target and the substrate support; and  
an annular magnet array disposed within the chamber to form a magnetic field that is substantially parallel to the surface of the substrate support, the annular magnet array being concentrically positioned about the surface of the substrate support.